

# APPLICATION DATA SHEET

Electronic Version 0.0.11

Stylesheet Version: 1.0

Attorney Docket Number: BUR920000077

Publication Filing Type: new-utility

Application Type: utility

Title of Invention: SINGLE REACTOR, MULTI-PRESSURE CHEMICAL VAPOR  
DEPOSITION FOR SEMICONDUCTOR DEVICES

Attorney Docket Number: BUR920000077

## Legal Representative:

Attorney or Agent: Mr. Robert A. Walsh Esq.

Registration Number: 26516

Customer Number Correspondence Address: 000000



## INVENTOR(s):

Primary Citizenship: U.S.A.

Given Name: Jack

Middle Name: O.

Family Name: Chu

Residence City: Manhasset Hill

Residence State: NY

Residence Country: US

Address: 44 Shelbourne Lane  
Manhasset Hill NY, 11040

Primary Citizenship: India

Given Name: Basanth

Family Name: Jagannathan

Residence City: Beacon

Residence State: NY

Residence Country: US

Address: 966 Wolcott Avenue

Beacon NY, 12508

Primary Citizenship: U.S.A.  
Given Name: Ryan  
Middle Name: Wayne  
Family Name: Wuthrich  
Residence City: Burlington  
Residence State: VT  
Residence Country: US  
Address: 161 Austin Drive, #67  
Burlington VT, 05401

09683088-1161